**Amendments to the Specification:**

Please replace the paragraph starting at page 11, line 21 with the following amended paragraph:

-- FIG. 3 is a perspective view of an input circuit and enclosure of a vacuum electron device in accordance with a specific embodiment of the present invention. A cover 302 houses a radio frequency (RF) connection to a vacuum electron device (VED) (not shown) and a high voltage connection (not shown) and a radio frequency (RF) compartment (not shown). Cover 302 is seated on top of VED enclosure 304. An RF input 306 is connected to the RF connection (not shown) inside cover 302 through the top of cover 302. An air input system 308 (external air connection) enters on top of cover 302 to allow air to circulate air within cover 302. The cover 302 also includes another external air connection 301 --

Please replace the paragraph starting at page 15, line 1 with the following amended paragraph:

-- FIG. 5B is a side elevation plan view of a guide plate and cover for a vacuum electron device enclosure in a closed position in accordance with an alternative specific embodiment of the present invention. A cover 500 is in a closed position and is seated on a VED enclosure (not shown). Shafts 506 and 508 are disposed inside track 502. Shaft ~~412~~ 508 comes into contact with sensor 408. The pressure applied on sensor 408 by shaft ~~412~~ 508 allows power to the high voltage connection. --

Please replace the paragraph starting at page 18, line 11 with the following amended paragraph:

-- FIG. 8 is a perspective elevation view of an adapter plate in accordance with a specific embodiment of the present invention. FIG. 9 is a cross sectional side view of an adapter plate in accordance with a specific embodiment of the present invention. As illustrated in FIG. 3, cover 302 is seated on top of VED enclosure 304. An adapter plate ~~902~~ 802 is used to divide VED enclosure 304 and provides an intimate seal for air and RF. Adapter plate ~~902~~ 802 has an opening ~~904~~ 804 for receiving a VED such that the exterior surface of the VED is in continuous contact with the surface defining opening ~~904~~ 804. --

Please replace the paragraph starting at page 19, line 9 with the following amended paragraph:

-- FIG. 10 is a perspective elevation view of an input circuit of a VED enclosure in accordance with a specific embodiment of the present invention. A cover 1002 has two chambers 1004 and 1006. Chamber 1004 forms a portion of an enclosure for a VED and has a first air passageway 1005. Chamber 1006 encloses a high voltage circuit for the VED and is connected to an air input system 1008 (not shown). Chamber 1004 has a second air passageway 1007. Both chambers 1004 and 1006 are separated by a panel 1010that allows air to circulate while RF is isolated. FIG. 10A is a top view of a cover 1002 containing an input circuit of VED enclosure in accordance with a specific embodiment of the present invention. FIG. 10B cross-sectional side plan elevation view

of an input circuit of a VED enclosure in accordance with a specific embodiment of the present invention. Chamber 1004 is connected to an RF input 1012.

Please replace the paragraph starting at page 19, line 20 with the following amended paragraph:

-- RF isolation is first accomplished using absorbing materials, such as tiles 1013 mounted on a flat surface within chamber 1004. Further isolation is accomplished by a partition on which panel 1010 also known as "honeycomb" or "waveguide beyond cutoff" EMI vent is mounted. Panel 1010 allows air to flow while cutting off RF from chamber 1004. Another purpose for panel 1010 is easy access for high voltage connection in chamber 1006. For example, panel ~~1008~~ 1010 can be mounted either with fasteners 1012 as illustrated in FIG. 10C, or with a quick-release system using keyhole slots 1014 as illustrated in FIG. 10D. --

Please replace the paragraph starting at page 22, line 1 with the following amended paragraph:

-- This new configuration allows all parts to be easily accessible by removing heater contact line 1222 with a simple tool. Heater contact line 1222 is fastened to contact block 1206 with screw threads 1228 and holds inner cathode line 1216 in place. As a result, inner cathode line 1216 with filter components 1230 attached can be removed. Filter components 1230 are mounted with an electrically nonconductive standoff, i.e. ceramic or nylon, and connected to an outer cathode line contact 1232 and an inner cathode line contact 1234 with contact fingers. Contact block 1206 also uses fingers to

contact inner cathode line 1216 and heater contact line 1222. For the heater contact line 1222, a wave washer or a plate washer with a tab for mounting may be used for contact. Contact block 1206 may be mounted to outer cathode line 1202 using flat-head screws ~~1230~~ 1240 radially inward. Screws ~~1230~~ 1240 are oriented that way instead of on the top of outer cathode line 1202 to avoid improper seating of a high voltage blocker ~~1232~~ 1242 to outer cathode line 1202. Vacuum ion pump contact 1212 may be mounted onto contact block 1206 via fasteners and modified to receive heater contact line 1222 as illustrated in FIG. ~~13~~ 12B. --

Please add the following new paragraph after paragraph starting at page 10, line 22:

-- FIG. 13 is a schematic side-view diagram of a VED under a cover in position in an enclosure in accordance with one embodiment of the present invention. --

Please add the following new paragraph after paragraph starting at page 22, line 1:

-- FIG. 13 illustrates the cover and enclosure of a Vacuum Electron Device (VED). The cover 1302 includes an input circuit 1312 coupled to the ceiling of the cover 1302. The input circuit also houses a socket 1314. The cover 1302 has two guides 1304, 1306 mating with a guide track 1310 from a guide plate 1308 as previously described. The socket 1314 is seated in an enclosure 1316 inside a frame 1318. The enclosure 1316 was previously described in FIGS. 7A, 7B, and 7C. --

Please replace the abstract with the following amended abstract.